

Phase correction by ellipsoidal focusing mirrors for a high-resolution neutron resonance spin echo spectrometer

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Collaborators:

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Masahiro Hino, Hisao Yoshinaga (Kyoto University),

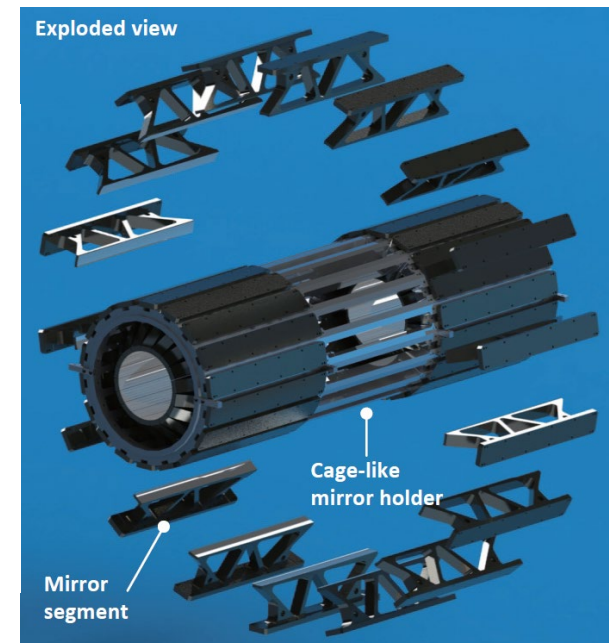
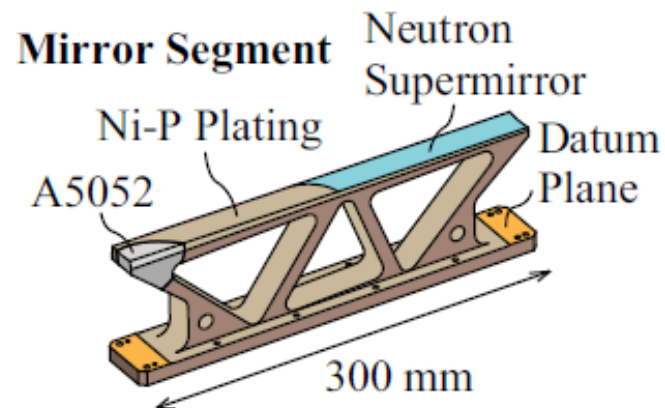
Fumiaki Funama (Oak Ridge National Laboratory),

Takuya Hosobata, Masahiro Takeda, Yutaka Yamagata

(RIKEN Center for Advanced Photonics)

Outline

1. Neutron resonance spin echo spectrometers at BL06 MLF, J-PARC
2. Phase correction by ellipsoidal focusing mirrors for neutron spin echo
3. Ellipsoidal neutron supermirror on metal substrate
4. Performance test
5. Summary



Collaborators

↑ M. Hino,
H. Yoshinaga
(KURNS, Kyoto Univ)



↑ H. Endo
(IMSS, KEK)

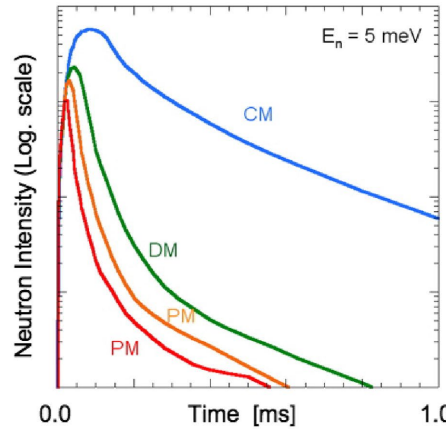
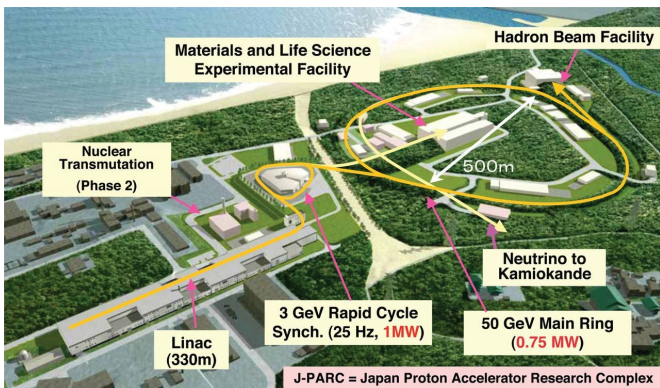


↑ T. Hosobata, ↑ Y. Yamagata,
T. Takeda
(RIKEN Center for Advanced
Photonics)



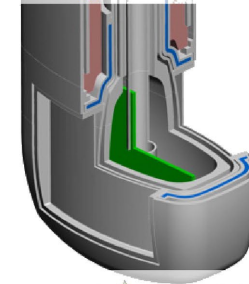
↑ F. Funama (PhD at Kyoto Univ, currently postdoc at ORNL)

Japan Spallation Neutron Source at MLF, J-PARC



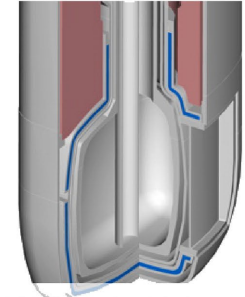
Poisoned Decoupled moderator (PM)

for high resolution



Decoupled moderator (DM)

for balanced performance



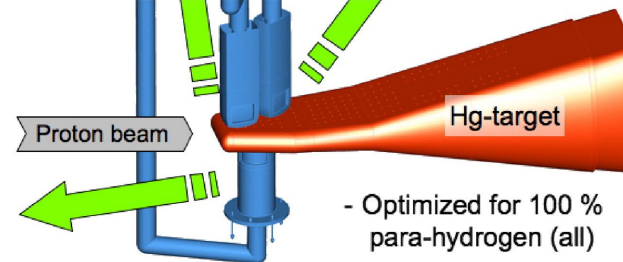
Coupled moderator (CM)

for high intensity



- large & cylindrical
- wide angle beam extraction

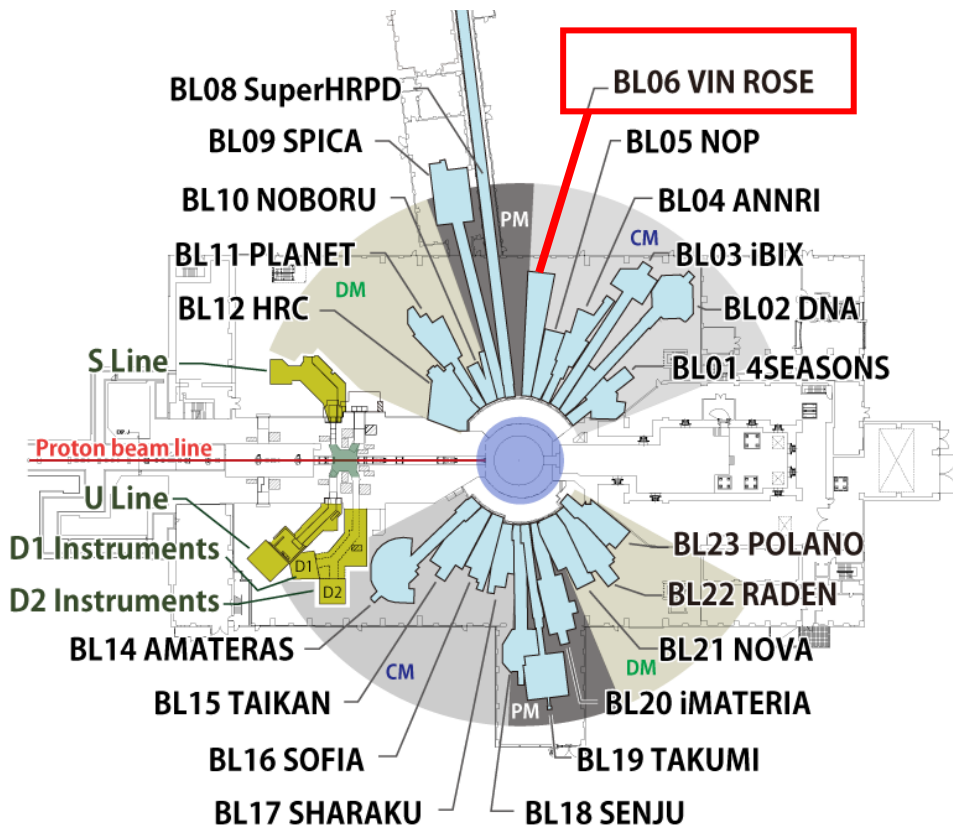
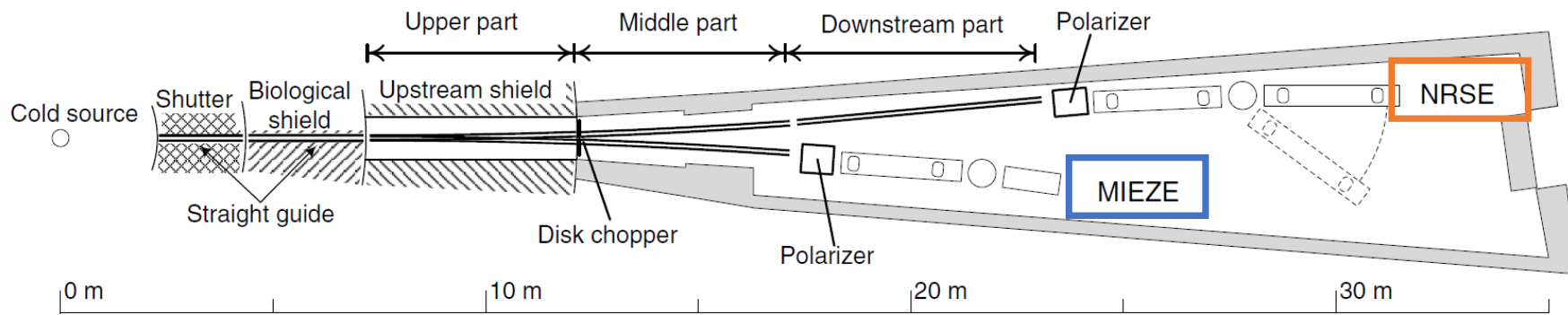
- Adoption of Ag-In-Cd (AIC) alloy for high decoupling energy at 1 eV
- optimized decouple coverage for lower pulse tail
- Adoption of Cd poison



- Optimized for 100 % para-hydrogen (all)

Proton beam power: 1MW (currently 0.8 MW)
Frequency: 25 Hz (TOF frame 40 ms)
Hg Target, Three types of moderator

BL06 at MLF, J-PARC



Constructed by KEK and Kyoto Univ

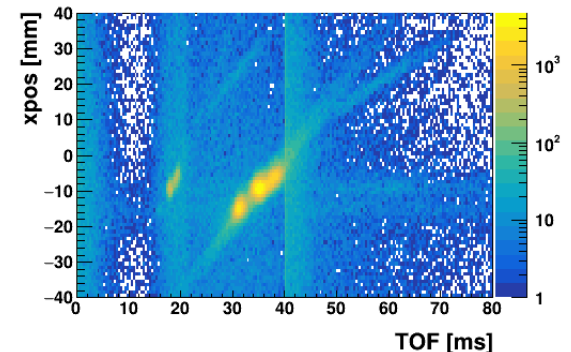
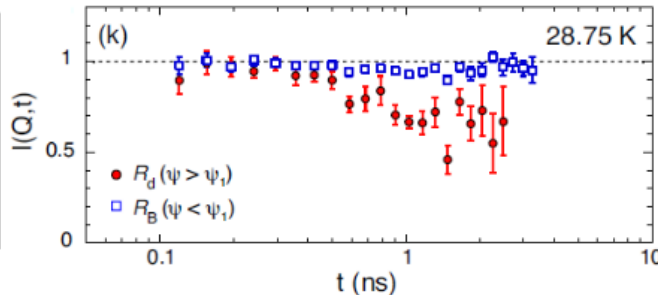
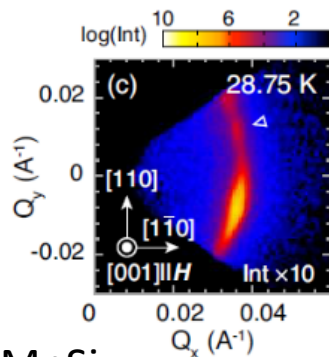
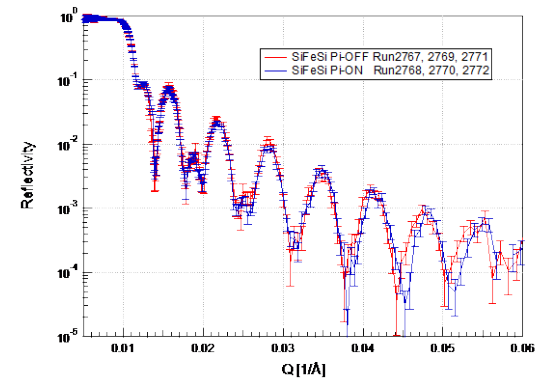
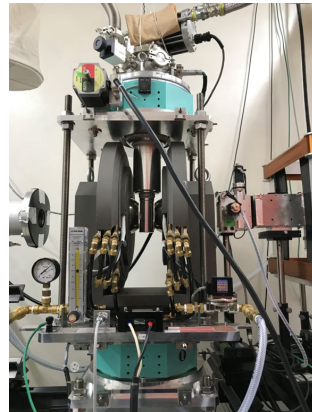
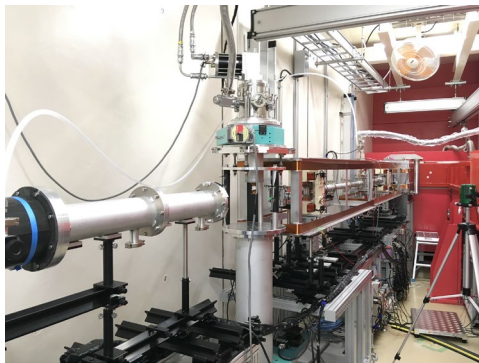
Village of neutron resonance spin echo spectrometers (VIN ROSE)



Two types of resonance-type spin echo at BL06:

- **NRSE (Neutron resonance spin echo)** for high energy resolution ($\tau > 100$ ns)
- **MIEZE (Modulation of intensity with zero effort)** \Rightarrow Open for users

Study of spin dynamics under a high magnetic field and other extreme conditions



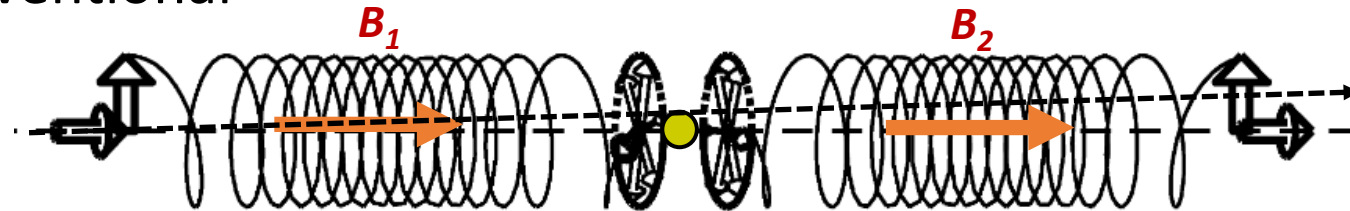
MnSi

T. Nakajima, Phys. Rev. Res. 2, 043393 (2020)

2. Phase correction approach using ellipsoidal focusing mirrors for neutron spin echo

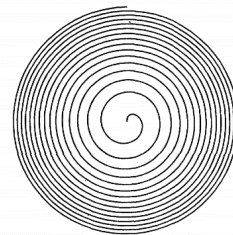
Larmor phase deviation in NRSE

Conventional
NSE

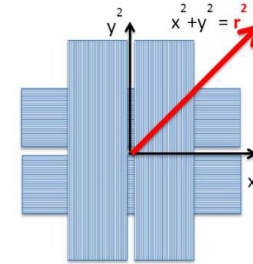


$$\phi = \frac{\gamma_n}{v} \int B_1 dl$$

M. Monkenbusch, et al., *C. R. Physique* 8 (2007)



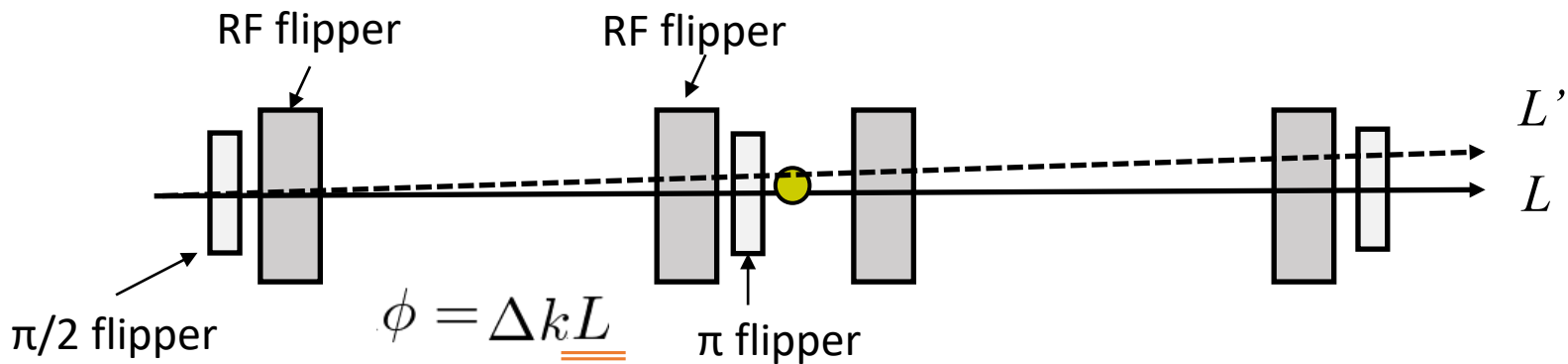
Fresnel
coil
(Neutron Data
Booklet, ILL)



Pythagoras
coil

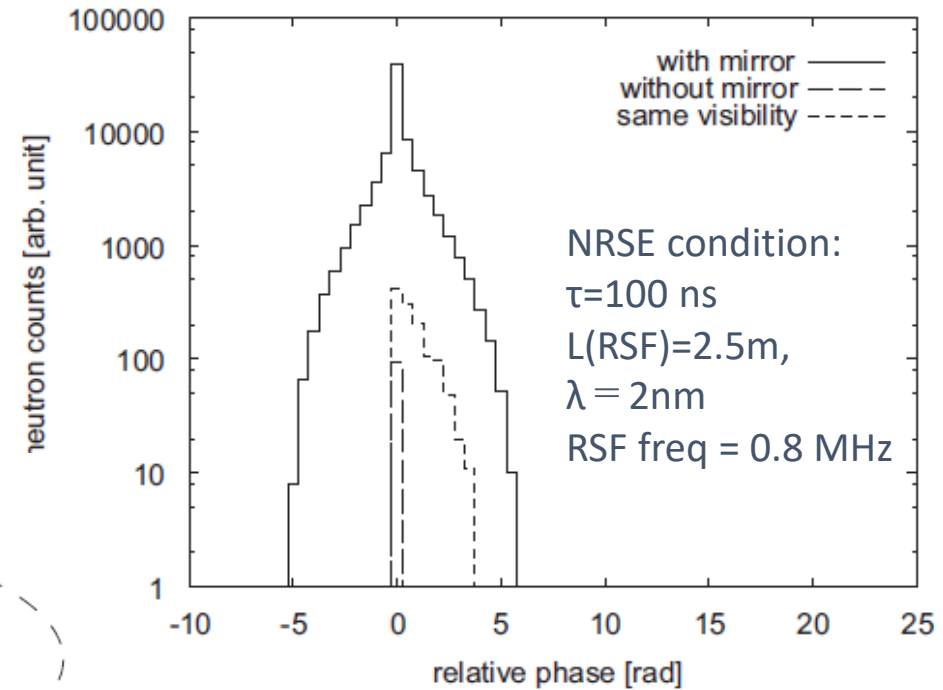
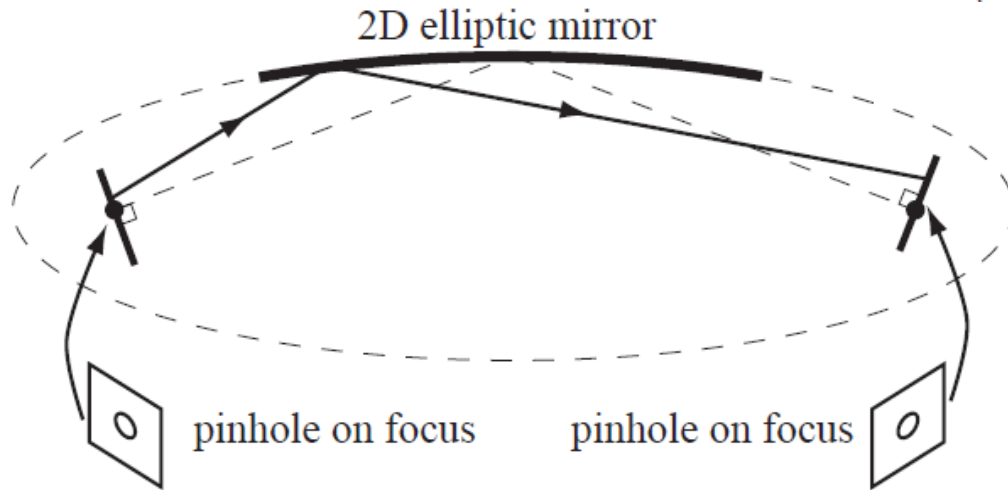
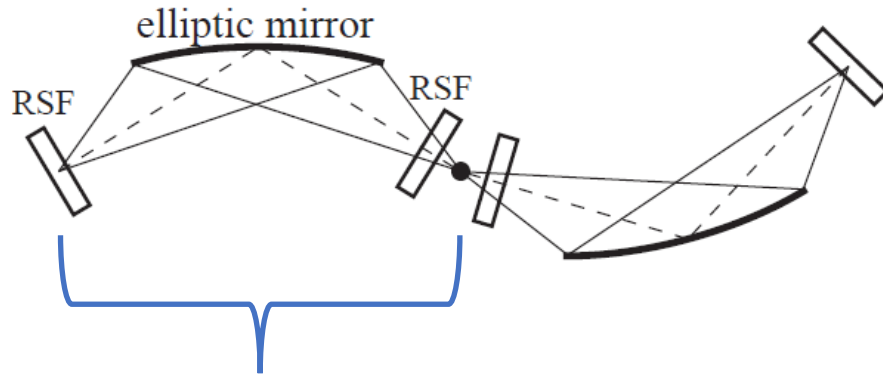
O. Ivanova, *J. Physics: Conf. Series* 862
012009 (2017)

NRSE (transverse)



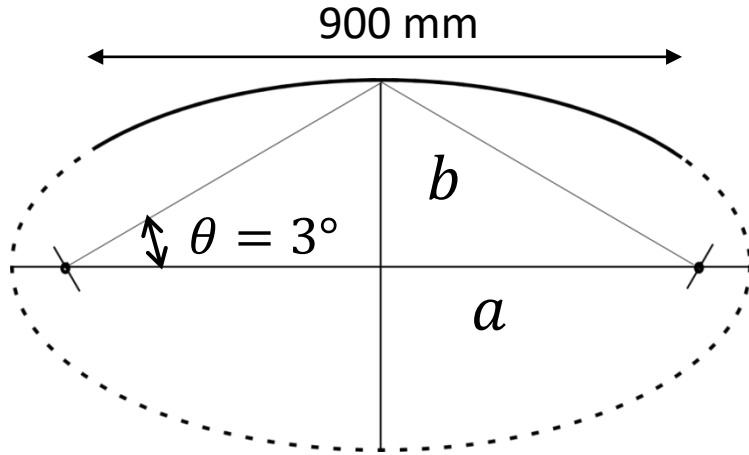
Divergent beam makes path deviation (phase deviation)

Phase correction (path length correction) approach by elliptic focusing mirror



On an elliptic the sum of distances from two focal points is constant

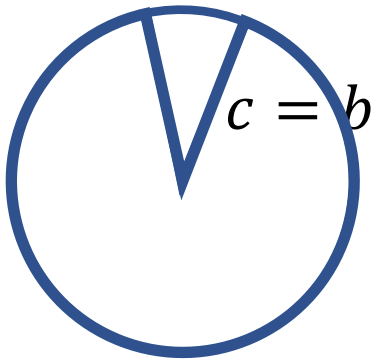
Ellipsoidal supermirror



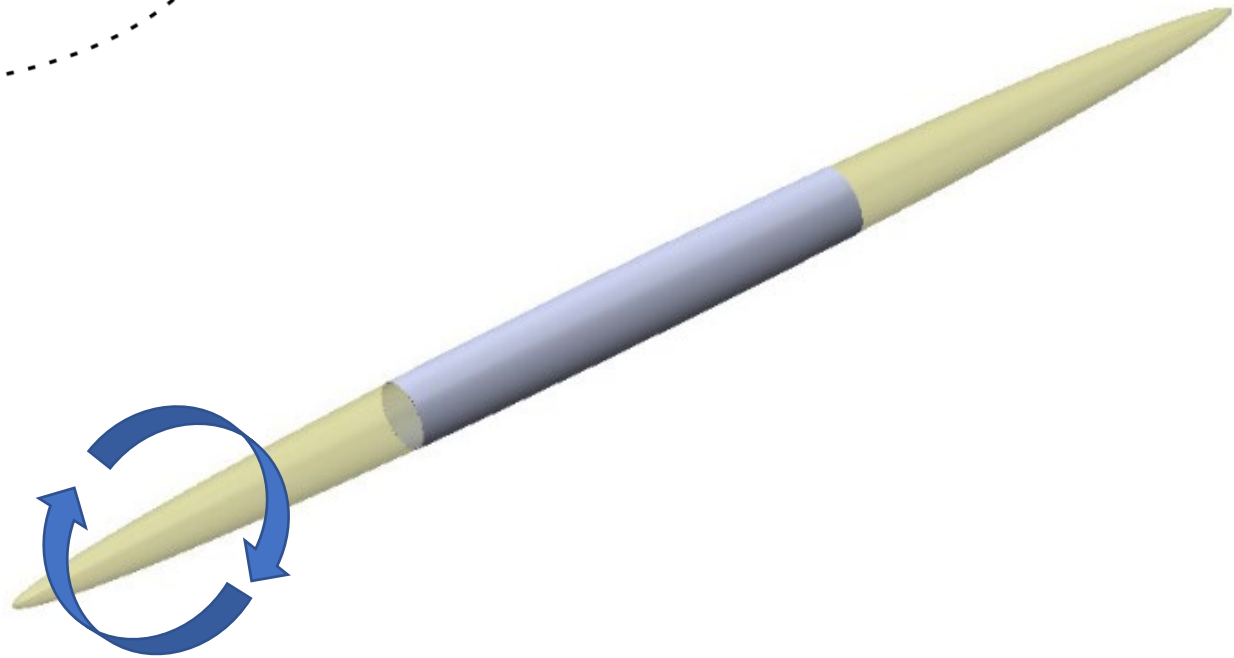
$$a = 1250 \text{ mm}$$

$$b = c = 65.4 \text{ mm}$$

$$\text{Focal length} = 2a = 2500 \text{ m}$$



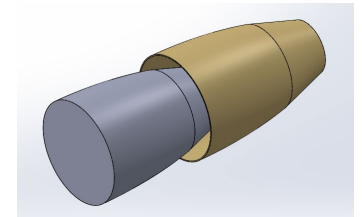
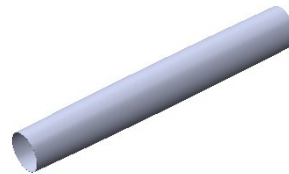
Full revolution!



3. Development and production of ellipsoidal neutron supermirror on metal substrate

Difficulties in realizing ellipsoidal mirror

- Surface flatness
- Supermirror deposition
- Accuracy of ellipsoidal form



Surface flatness

By courtesy of Dr. Hosobata

substrate material

- ✓ Amorphous → glass
- ✓ Single crystal → silicon
- ✗ Polycrystalline → metal



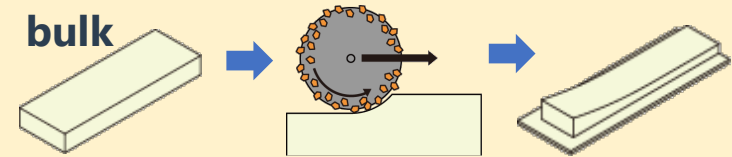
Roughness due to crystal grains

Bending
(Float glass, Silicon wafer)



Limitation on deformed shape

Grinding of bulk materials



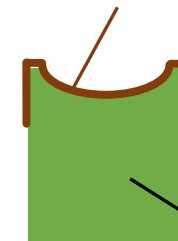
Time-consuming & high cost

Our solution: Electroless Nickel-Phosphorus plating

Coatings for optical
element molds



NiP amorphous plating



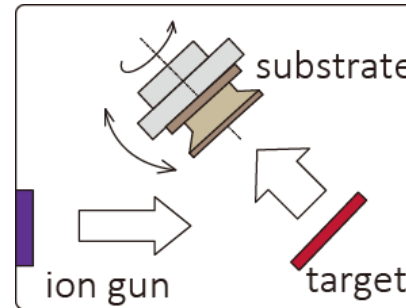
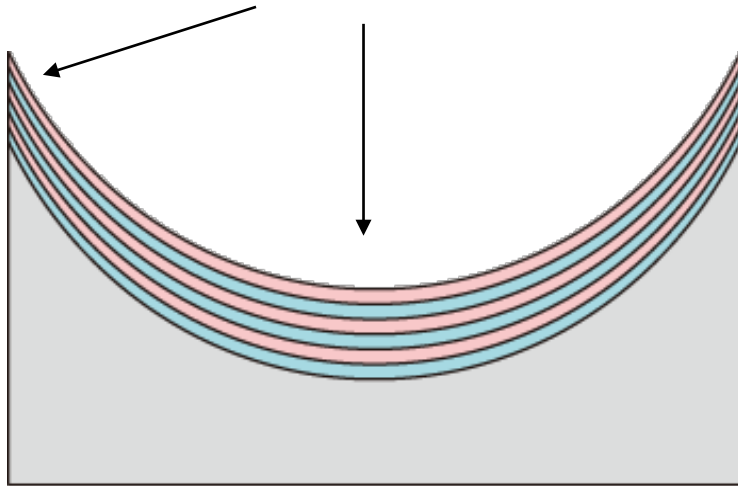
Easily
machinable
metals

Phosphorus content	Structure
1 – 4 %	Polycrystalline
5 – 8 %	(Intermediate)
9 – 12 %	Amorphous

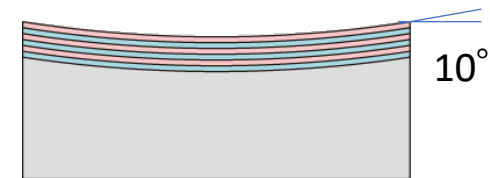
Supermirror deposition

By courtesy of Dr. Hosobata

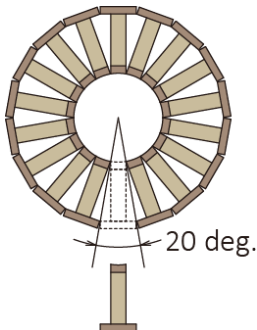
☹️ Steep curve makes non-uniformity of deposition



Rotating & tilting workpiece \Rightarrow uniform deposition on $\pm 10^\circ$ inclined surface

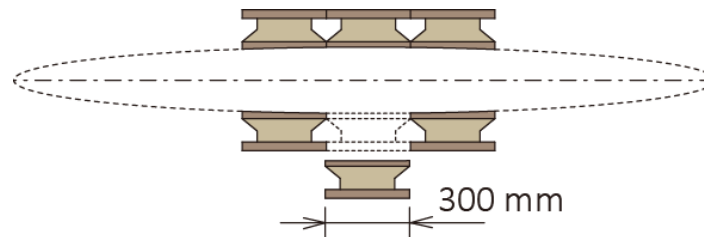


18 sectors



×

3 longitudinal divisions



=

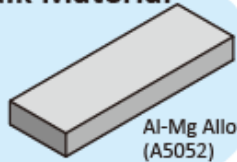
54

segments

Overview of mirror production

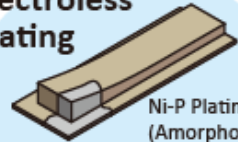
By courtesy of Dr. Hosobata

Bulk Material



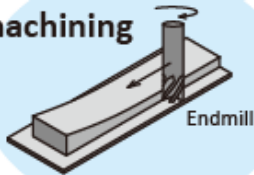
Al-Mg Alloy
(A5052)

Electroless Plating



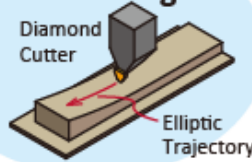
Ni-P Plating
(Amorphous,
 $t = 100 \mu\text{m}$)

Pre-machining



Endmill

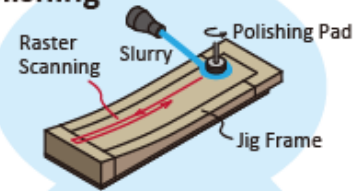
Precise Figuring by Diamond Cutting



Diamond
Cutter

Elliptic
Trajectory

Polishing



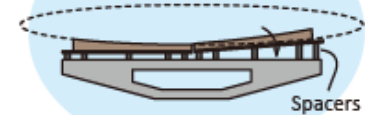
Raster
Scanning

Slurry

Polishing Pad

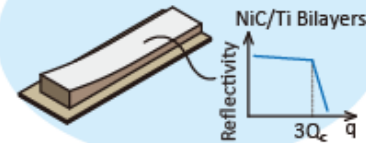
Jig Frame

Assembly & Adjustment



Spacers

Supermirror Deposition by Ion Beam Sputtering



NiC/Ti Bilayers

Reflectivity

$3Q_c$ q



Left to right:

*Al-Mg pre-machining
(easily machinable metal)

*Ni-P plating
(Amorphous)

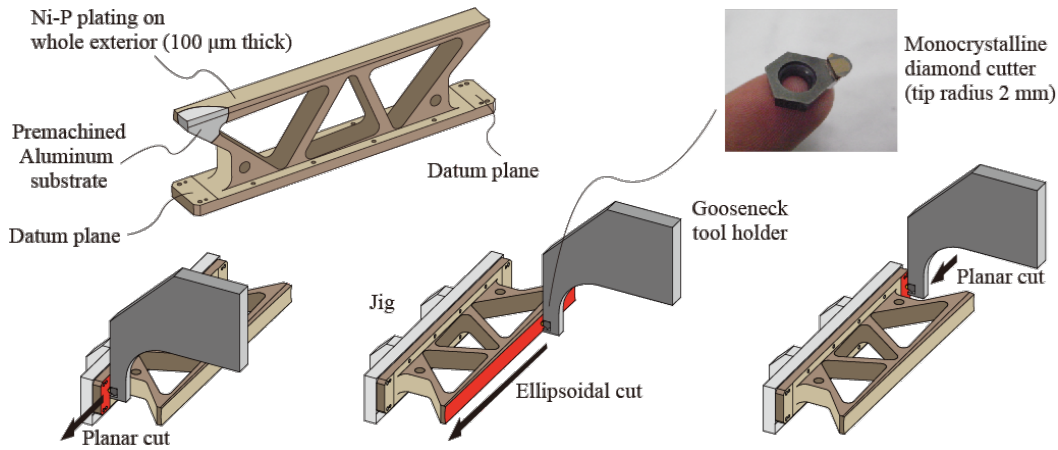
*Diamond cut
(high-precision figuring)

*Polishing
(remove roughness)

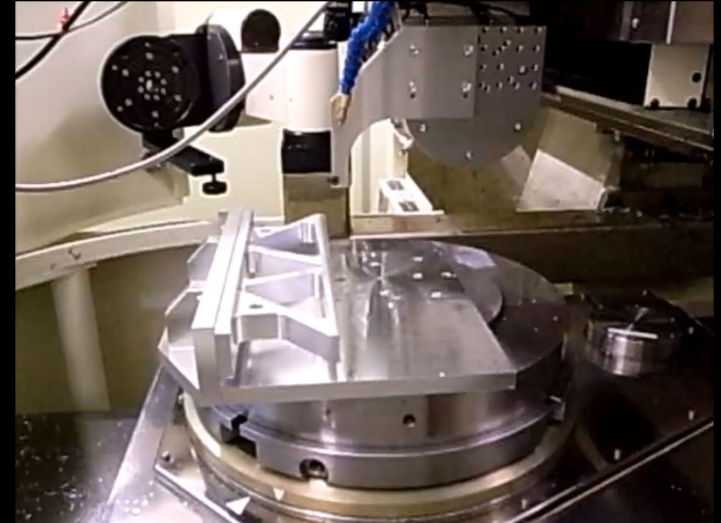
Precise figuring process

By courtesy of Dr. Hosobata

One chuck processing for the curved surface and datum plate



Demonstration of cutting (x 8)

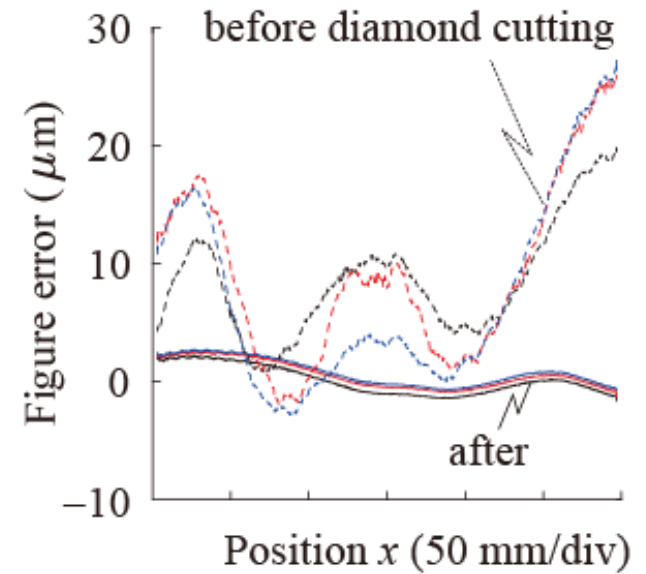
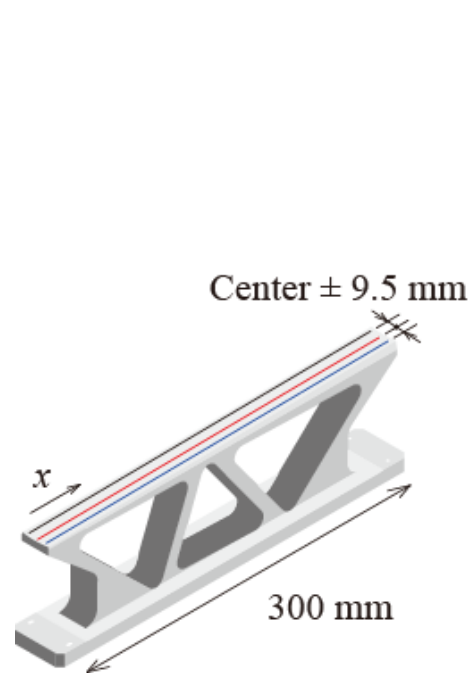
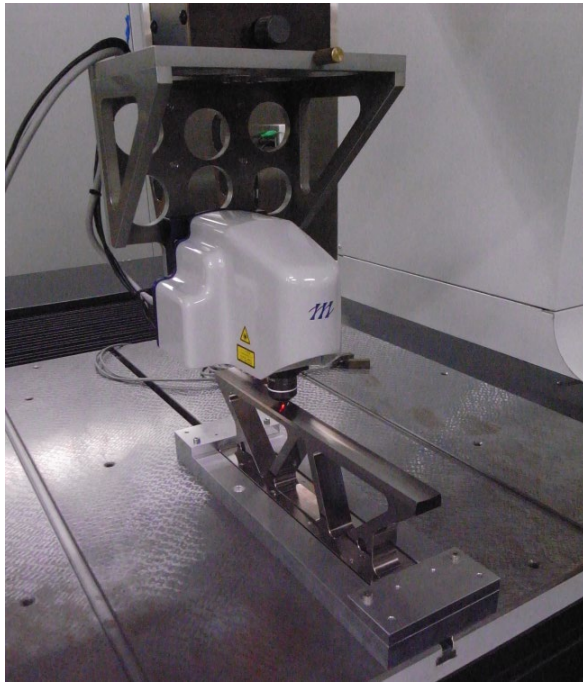


NAGASE i NPIC-M200
(Positioning resolution : 10 nm)

Relative position accuracy between the datum plane and curved surface
≡ Precision of ultra-precision machining center

Figure error

By courtesy of Dr. Hosobata

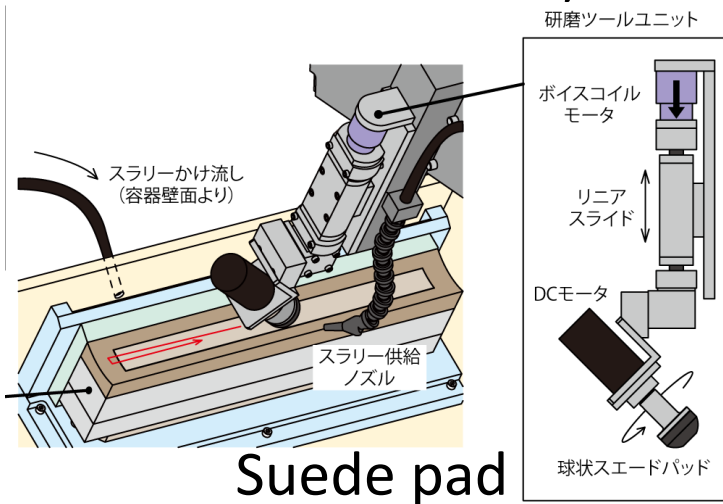


Laser AF probe (Mitaka Khoki PFU-3)
on 3D measuring instrument (Mitsutoyo Legex)

Polishing process

By courtesy of Dr. Hosobata

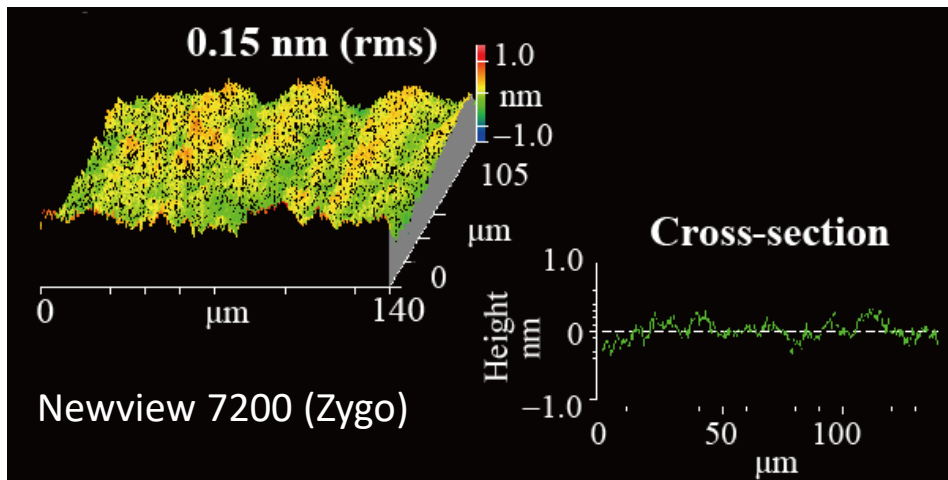
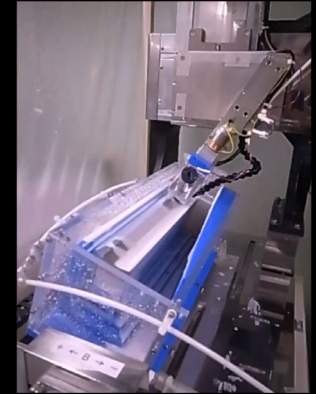
Slurry (alumina 300 nm →
colloidal silica 80 nm)



Demonstration (x8)



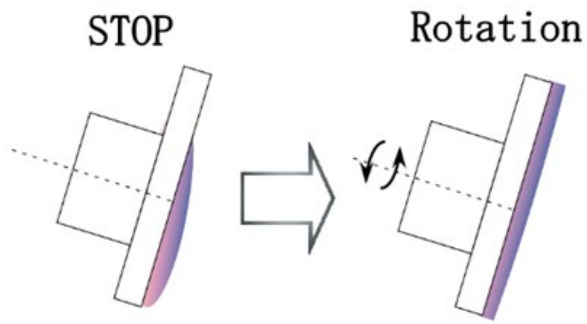
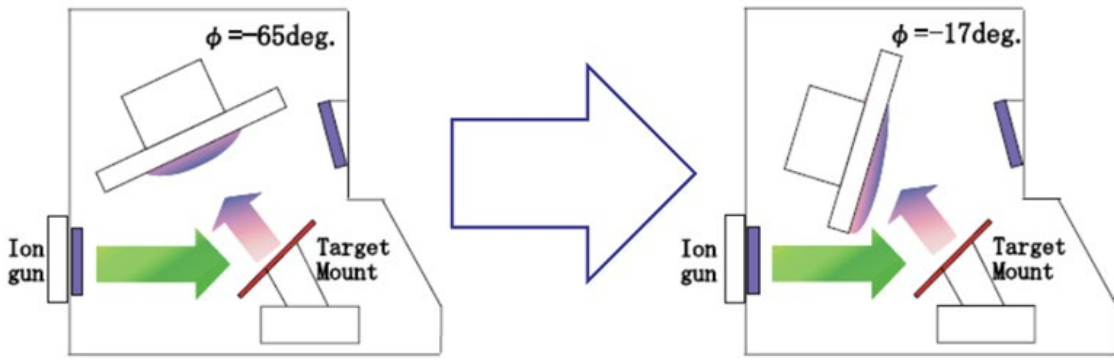
Polishing process



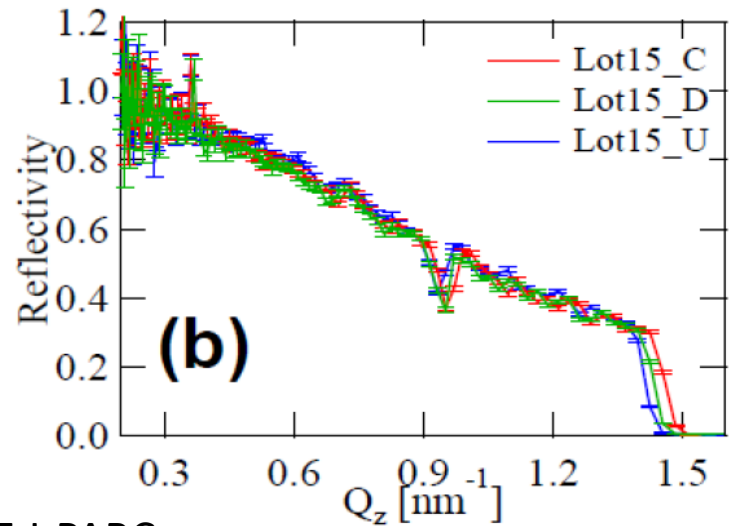
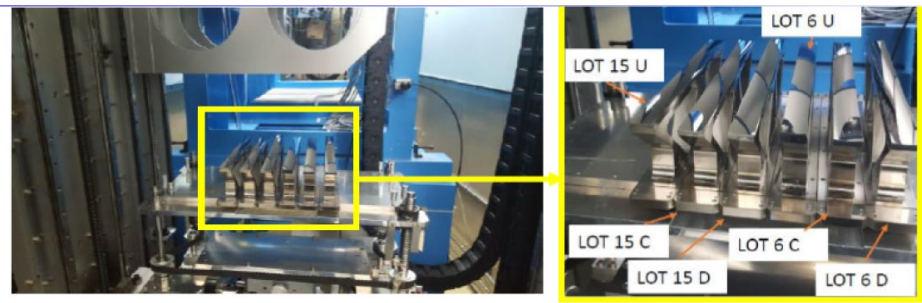
Cutter mark removal with
alumina + Finishing with
colloidal silica ⇒
Roughness < 0.2 nm (rms)
in 24 hours

Supermirror ion beam sputtering deposition

By courtesy of prof. Hino

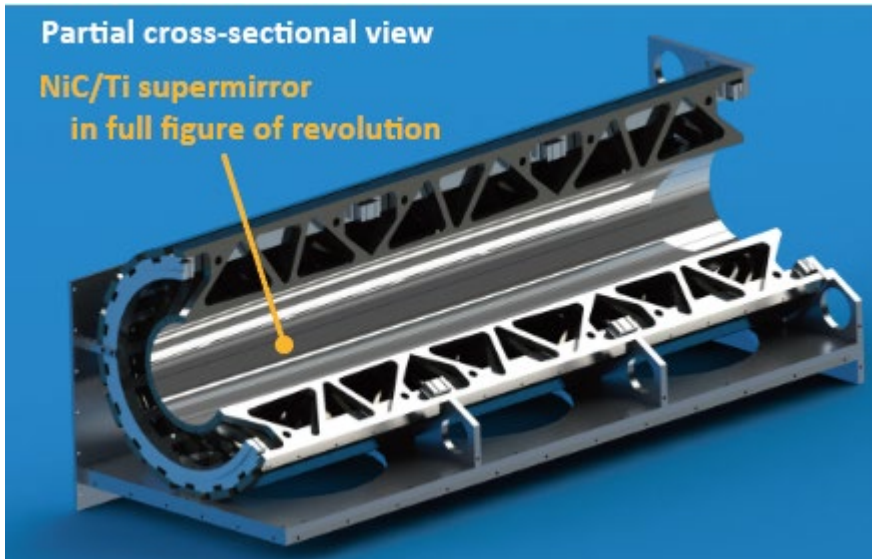
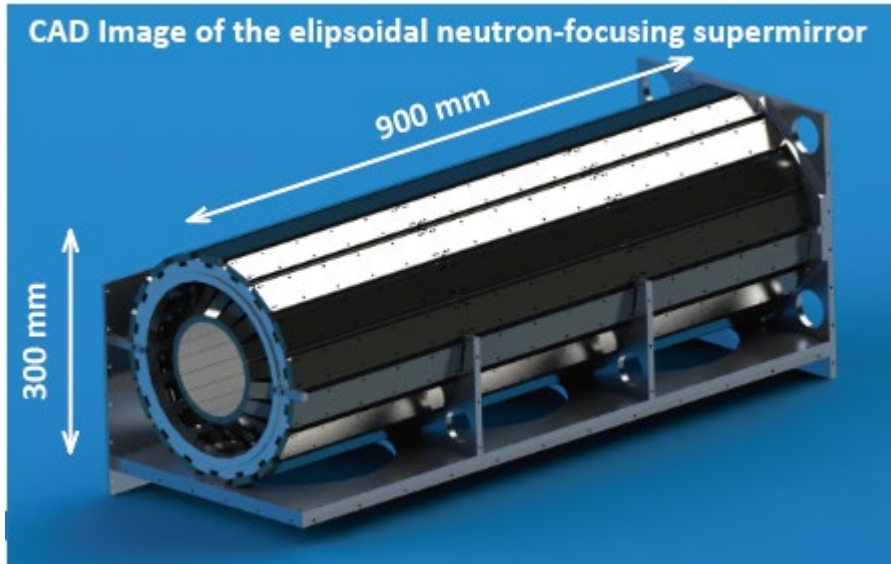


Rotating & tilting substrate \Rightarrow
Uniform deposition in wide area



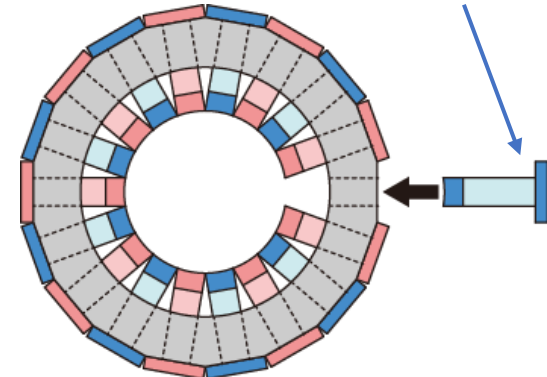
Reflectivity measurement of $m=6.5$ mirror at BL16 MLF J-PARC

Cage-like assemble holder

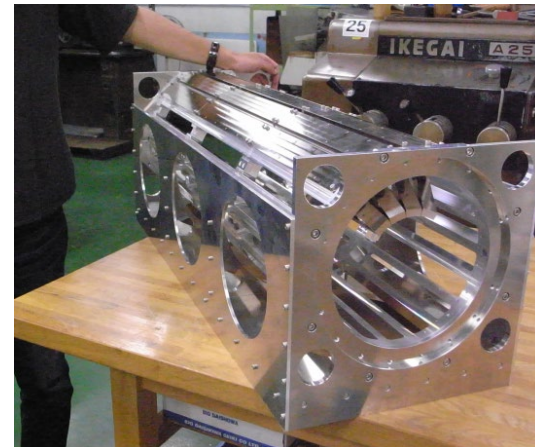


T. Hosobata et al., JPS Conf. Proc. (2018)

Datum plate in outer circumference



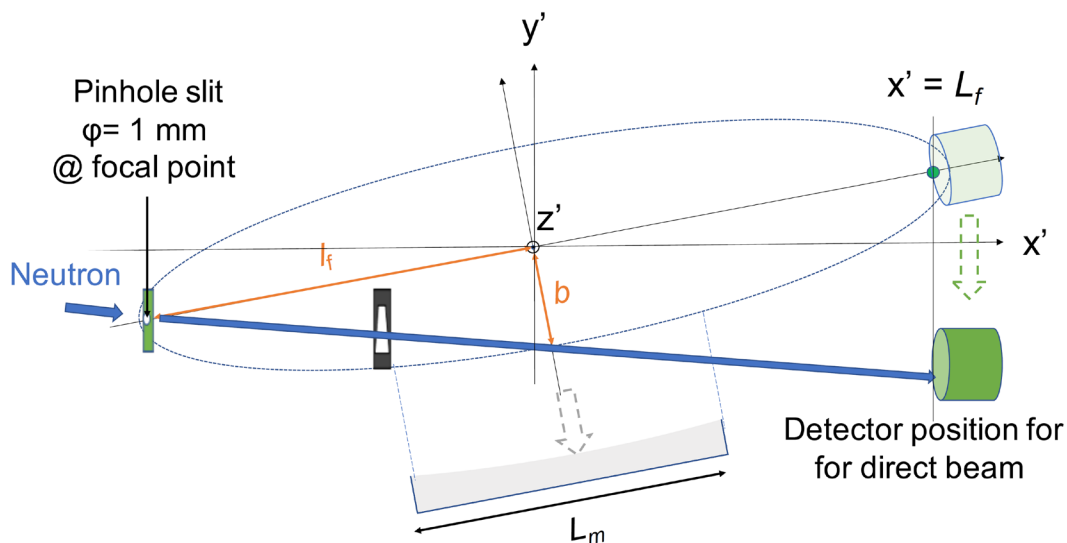
- Easy measurement
- Mirror and datum plane are oriented in the same direction



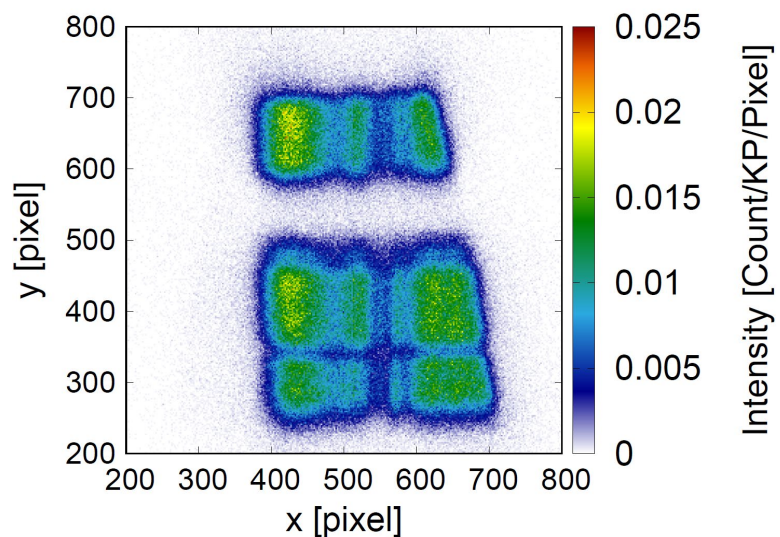
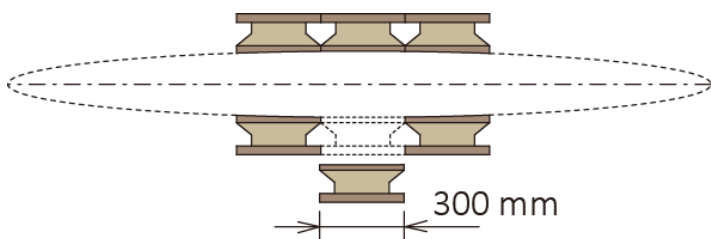
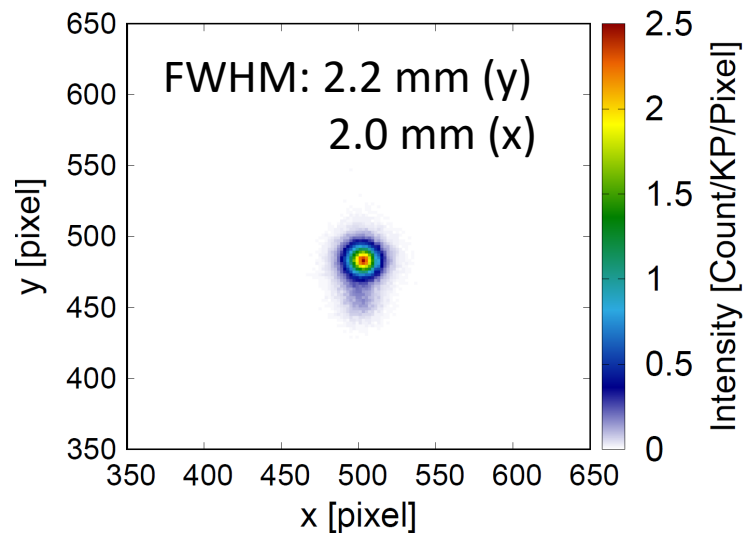
Metal substrate allows a flexible design

4. Performance test

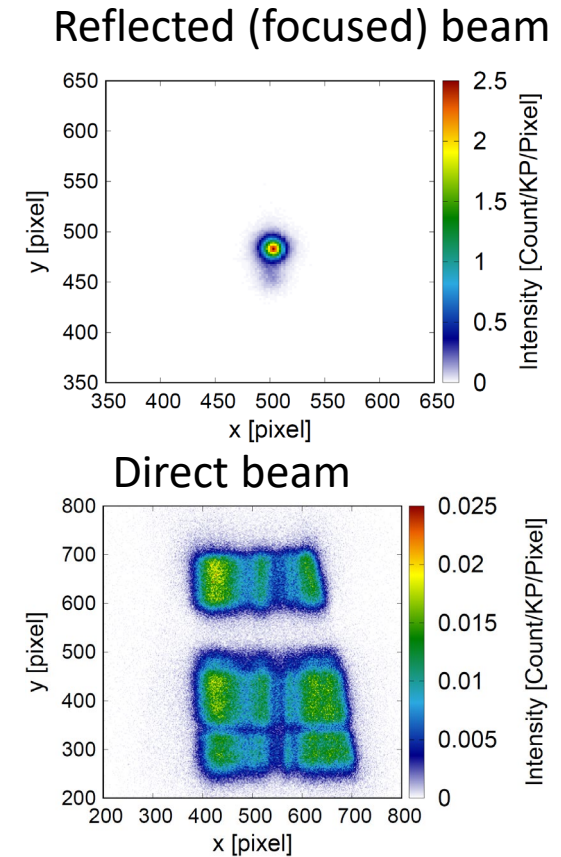
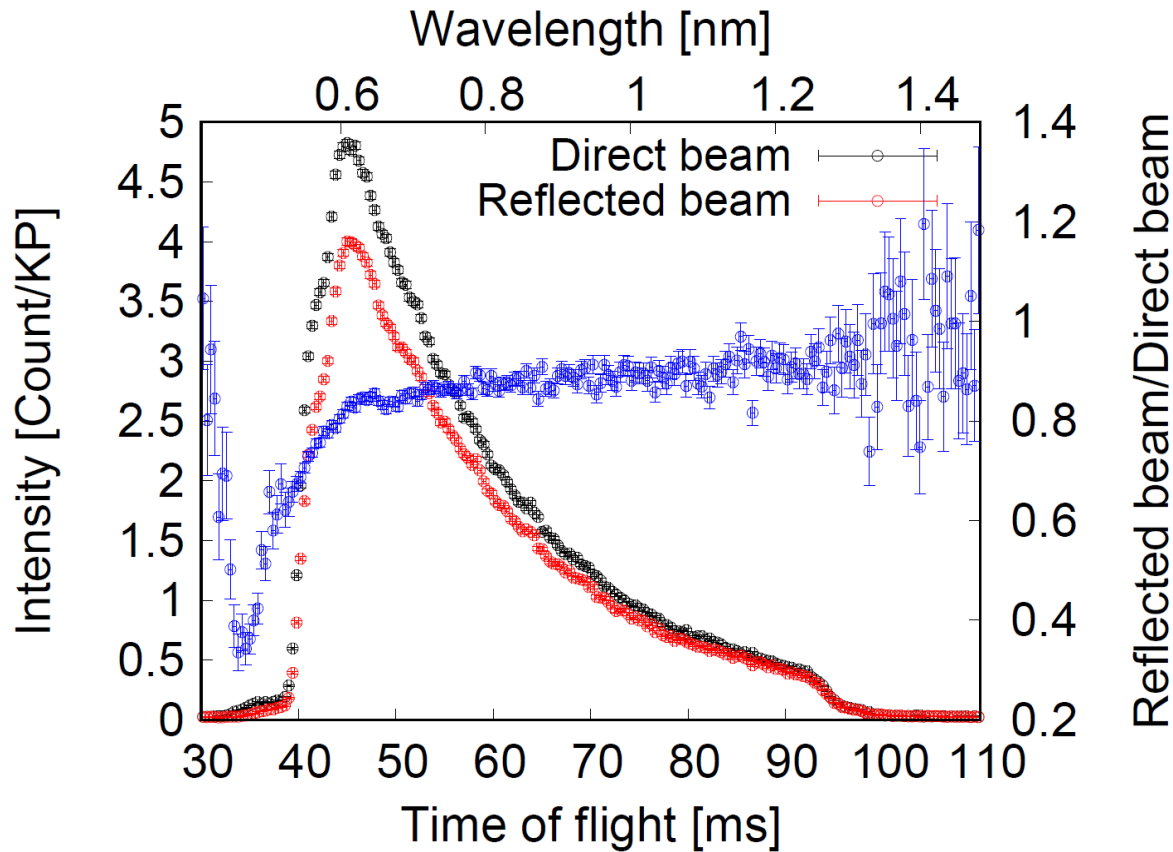
Performance test of single sector



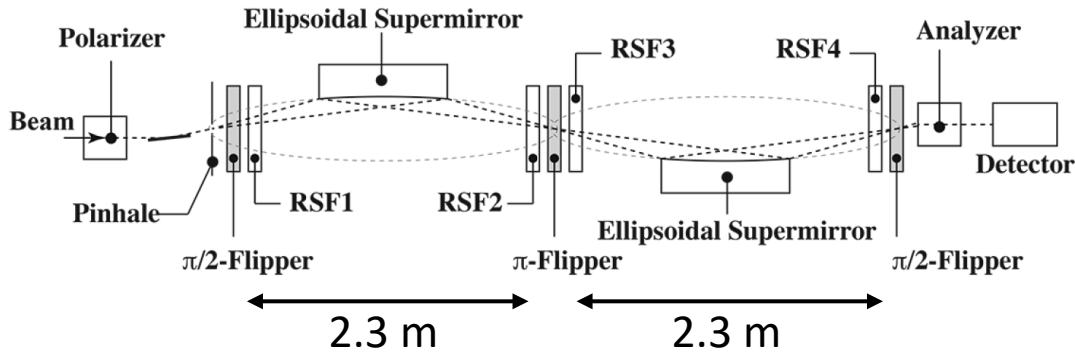
Reflected (focused) beam



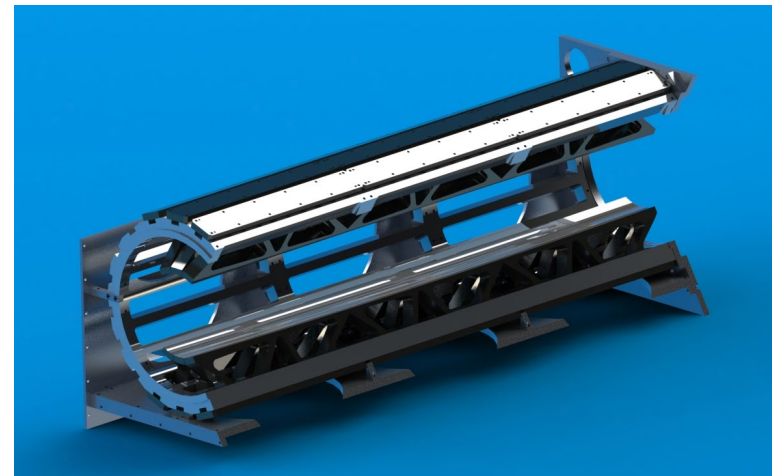
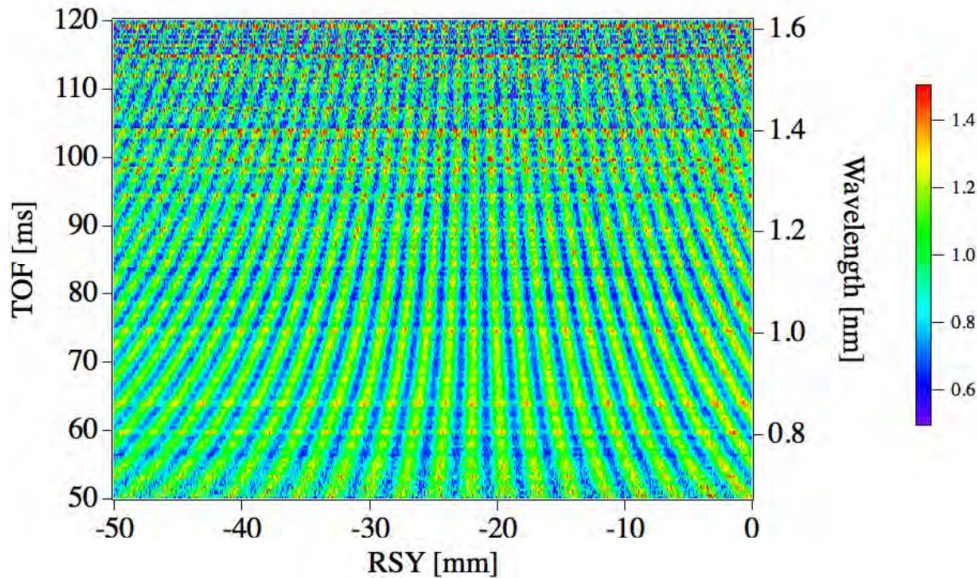
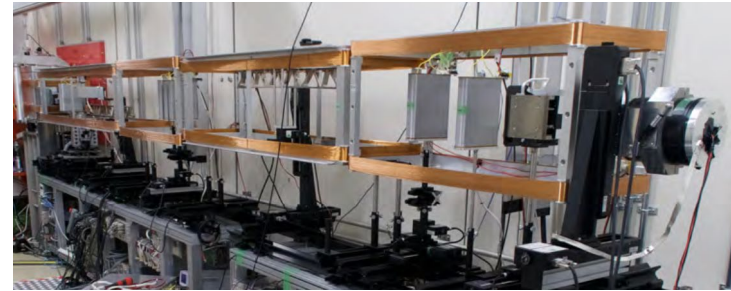
Performance test of single sector



NRSE signal using sector mirrors

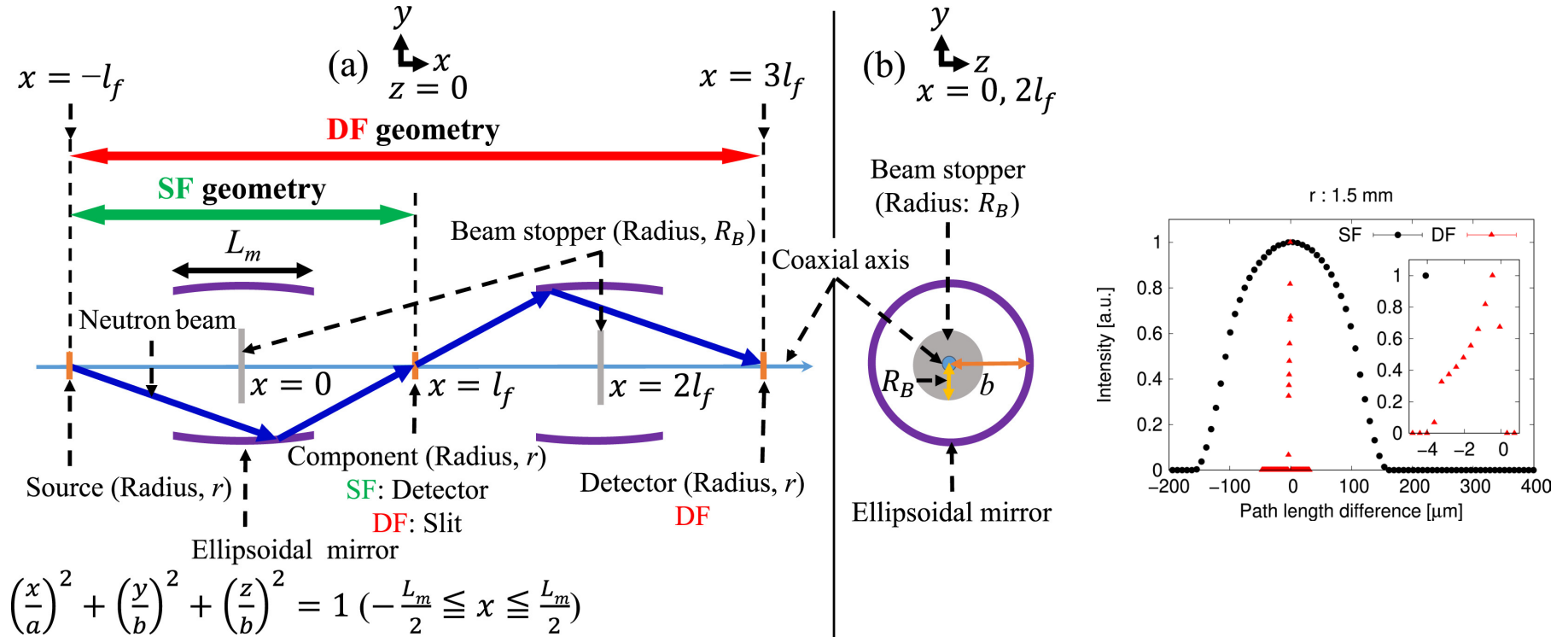


RSF1, 2, 3, 4 were operated at $f = 100$ kHz
 The supermirrors m-value were $m = 5$.



36 segments to be tested

Simulation of double focusing for coma aberration correction



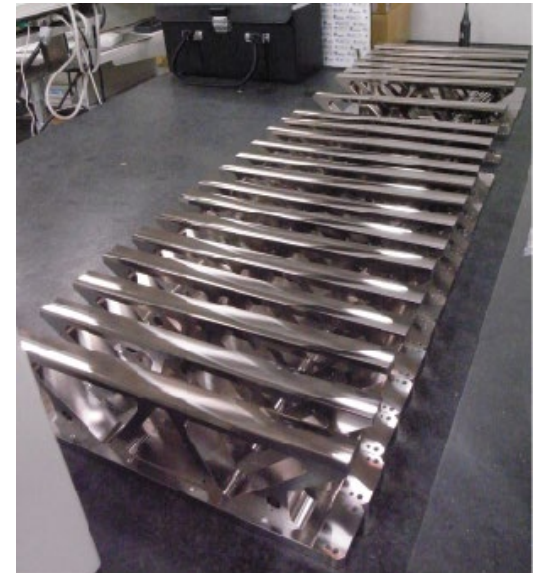
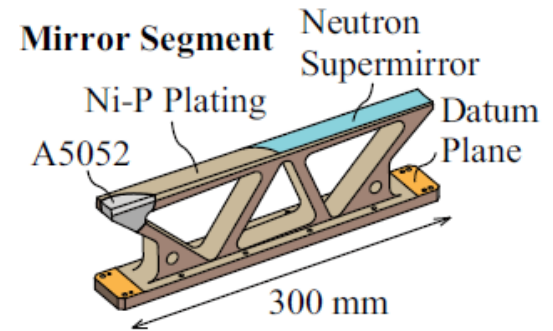
F. Funama, T. Tasaki M. Hino, T. Oda, H. Endo,
Nucl. Instrum. Methods A, 1010 165480 (2021).

Two reflections with elliptical mirrors
to eliminate coma aberration

Summary

- Ellipsoidal mirrors with $m=6.5$ supermirror on Ni-P plated metal substrate
- Segmental divided design for the deposition uniformity and machining space
- Design and basic performance test have been completed and mass production has begun

Most of the materials on the mirror fabrication are by courtesy of Dr. Hosobata at RIKEN.



Thank you for your attention

